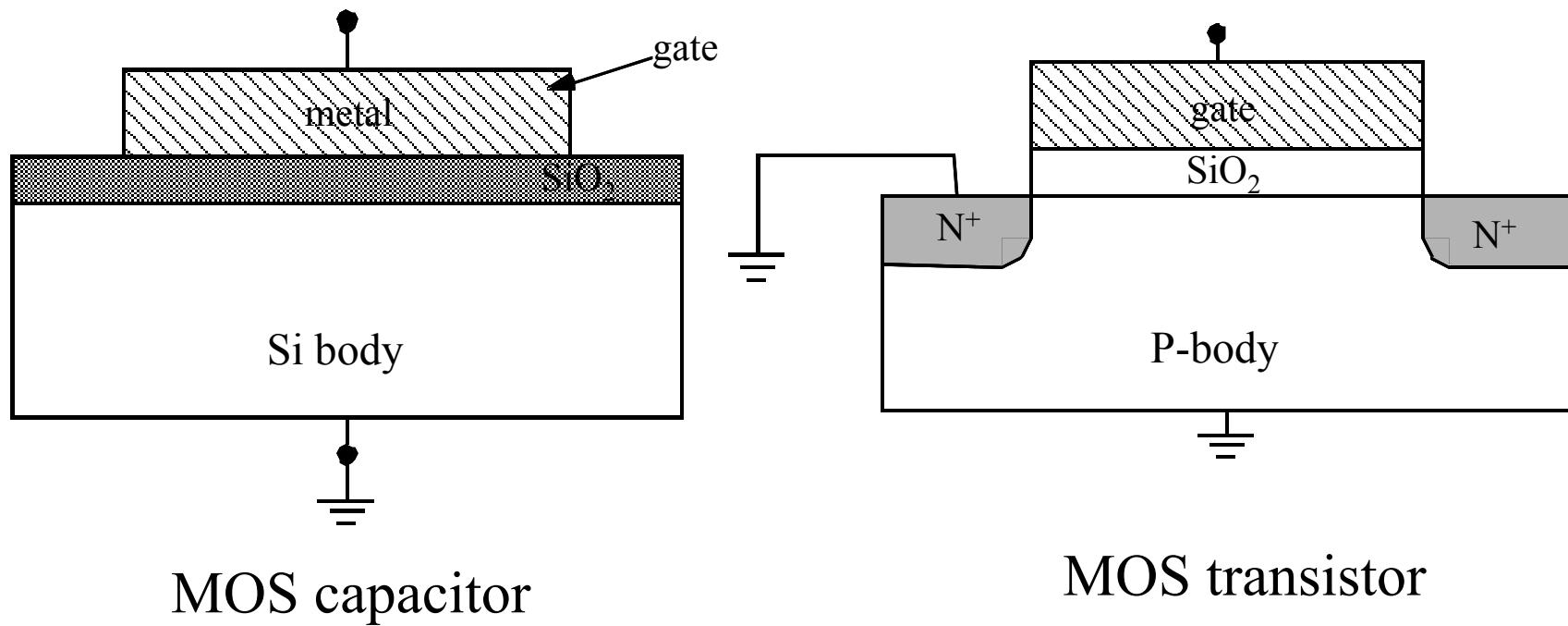
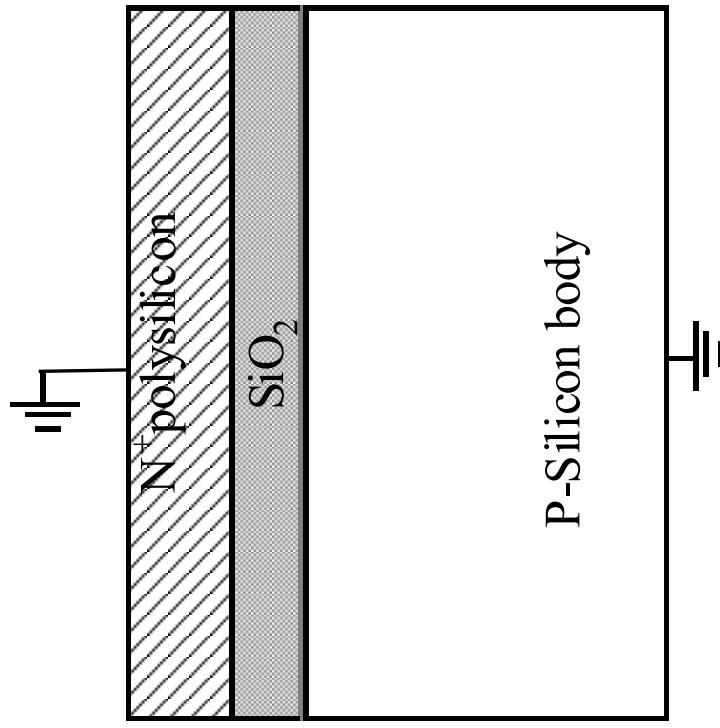


# *Chapter 5 MOS Capacitors*

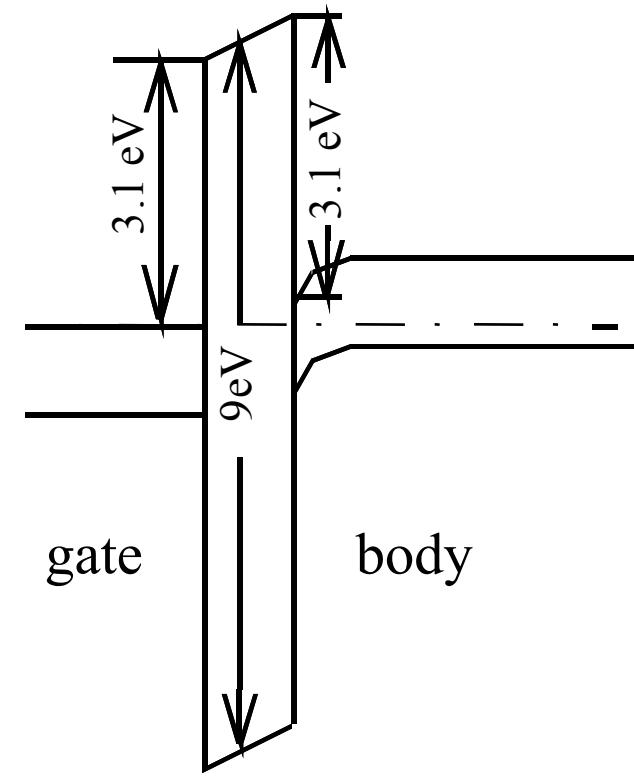
MOS: Metal-Oxide-Semiconductor



# *Chapter 5 MOS Capacitors*



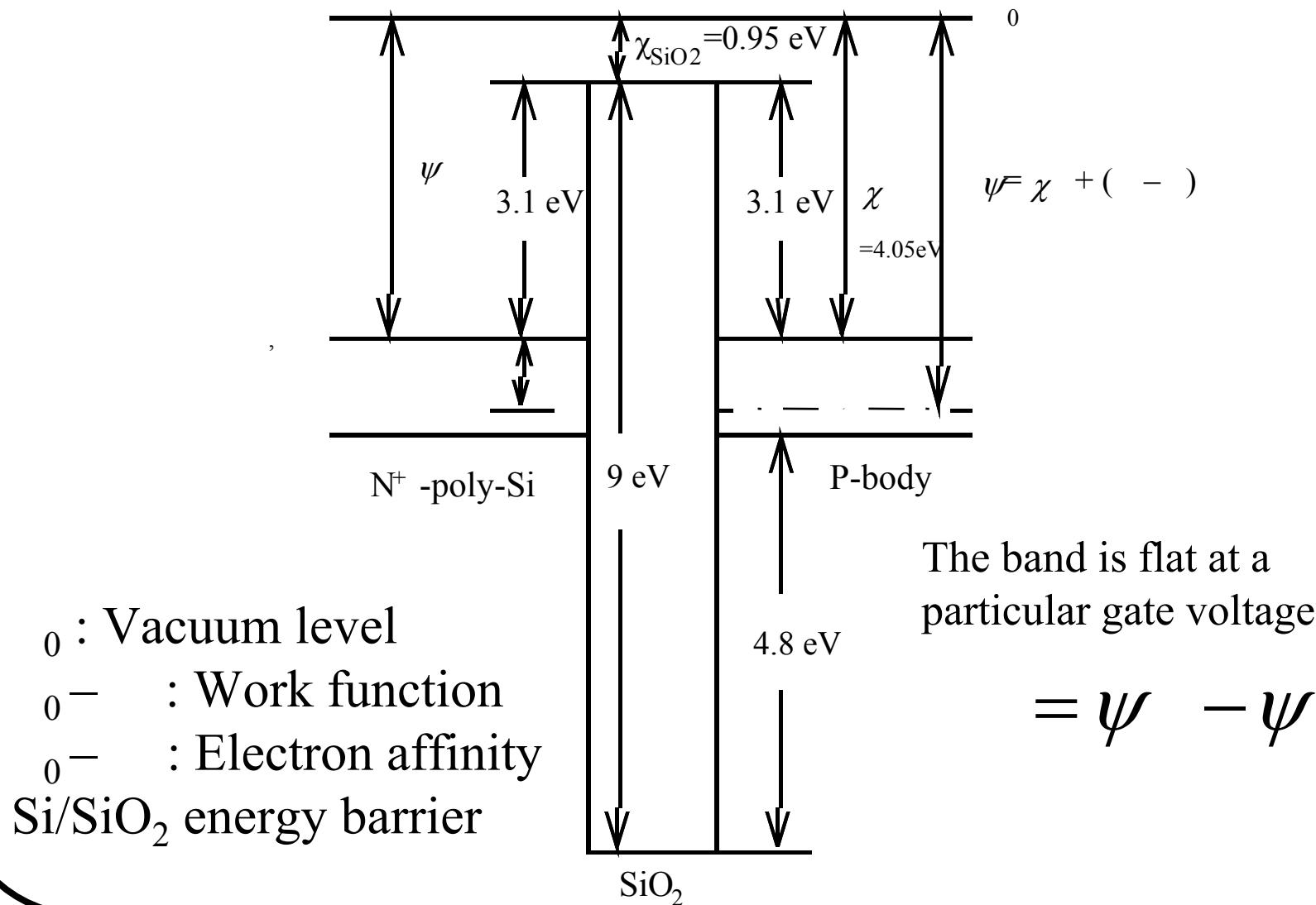
(a)



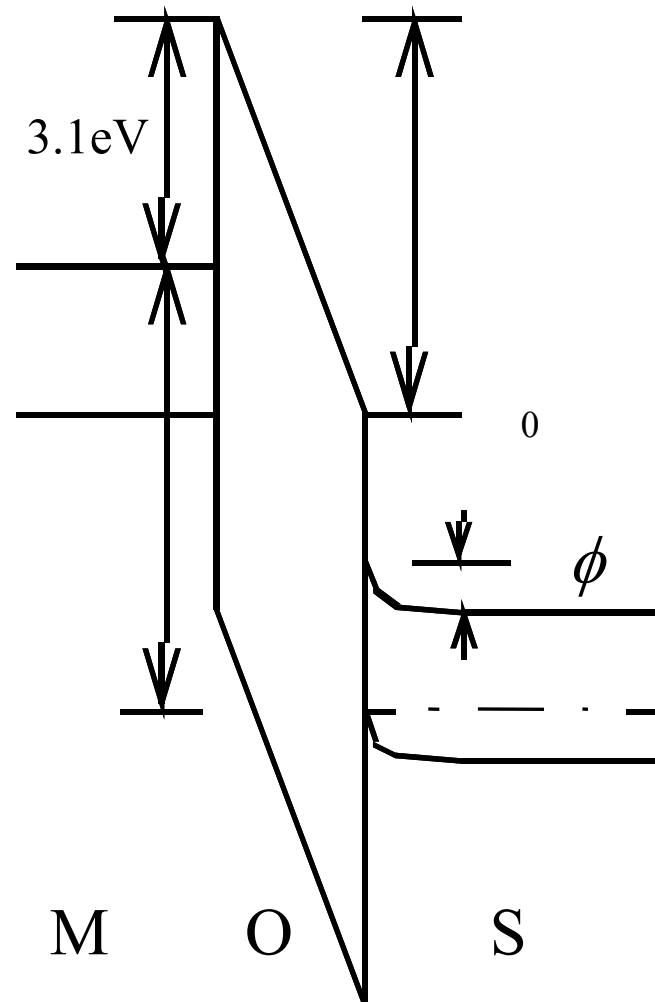
(b)

How does one arrive at this energy-band diagram for  $V_g = 0$ ?

## 5.1 Flat-band Condition and Flat-band Voltage



## 5.2 Surface Accumulation



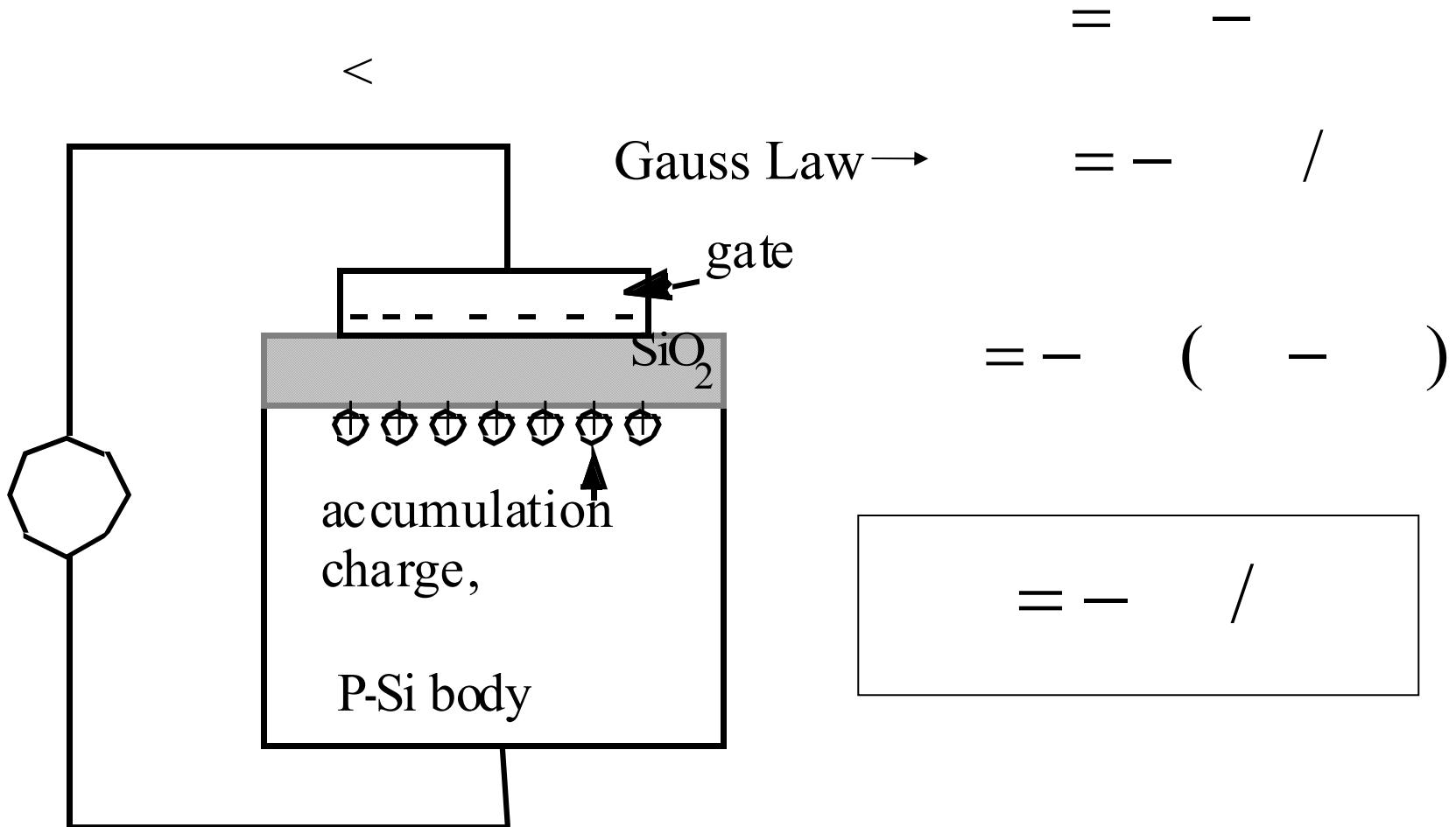
Make  $< .$

$$= + \phi +$$

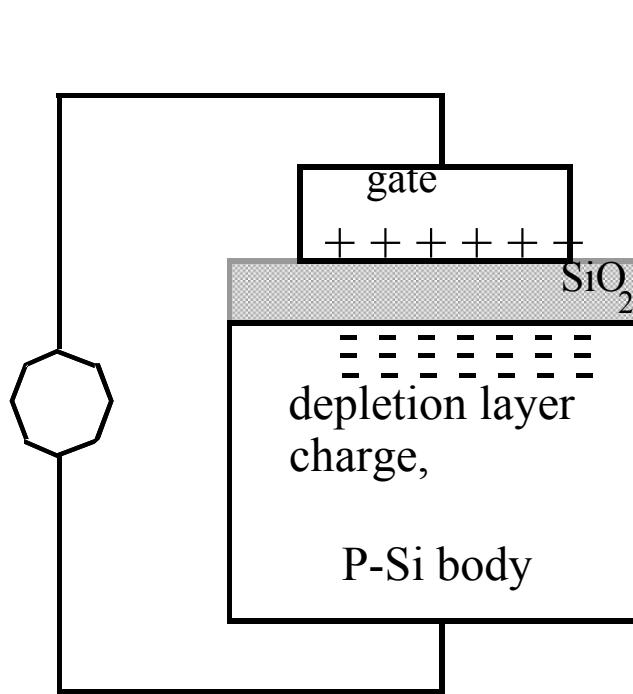
$\phi$  : surface potential, band bending  
: voltage across the oxide

$\phi$  is negligible when the surface is in accumulation because a little band-bending leads to a large accumulation charge.

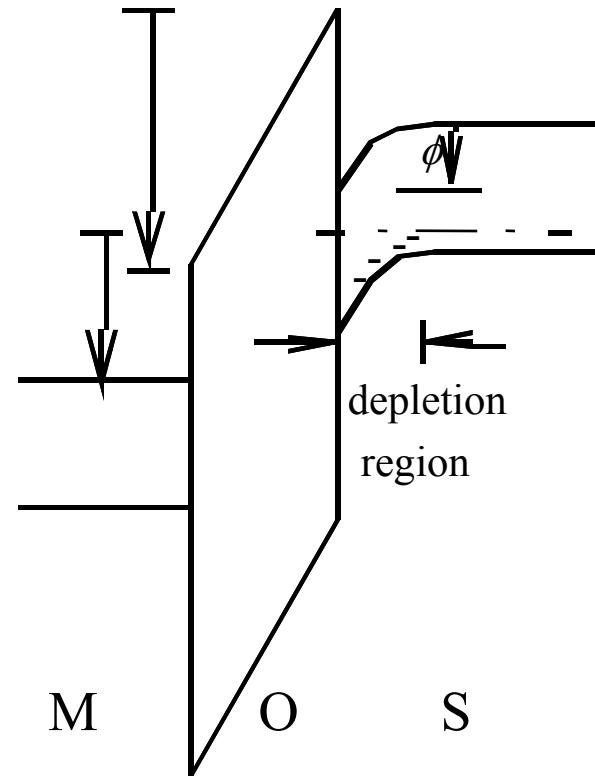
## 5.2 Surface Accumulation



## 5.3 Surface Depletion



(a)



(b)

$$= \dots = \dots = \dots = \sqrt{\frac{2\epsilon \phi}{V_g - V_{fb}}}$$

## 5.3 Surface Depletion

$$= +\phi + = +\phi + \frac{\sqrt{2\varepsilon\phi}}{}$$

Can this equation be solved to yield  $\phi$  ?

## 5.4 Threshold Condition and Threshold Voltage

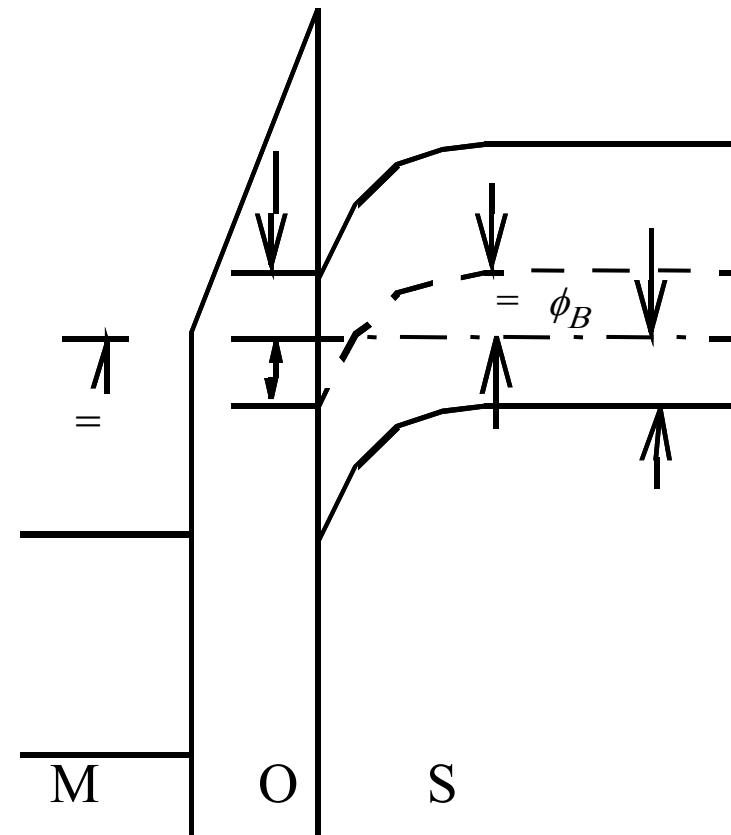
**threshold (of inversion)**

**threshold :**                   , or

(       )           (       )      or

❖ and

$$\phi = 2\phi = 2 - \ln\left(\frac{M}{S}\right)$$



$$\phi = \frac{1}{2} - (\phi_M - \phi_S) = -\ln\left(\frac{M}{S}\right) = -\ln\left(\frac{\phi_M}{\phi_S}\right) = -\ln\left(\frac{\phi_M}{\phi_S}\right)$$

## *Threshold Voltage*

$$= \phi + \frac{V}{2}$$

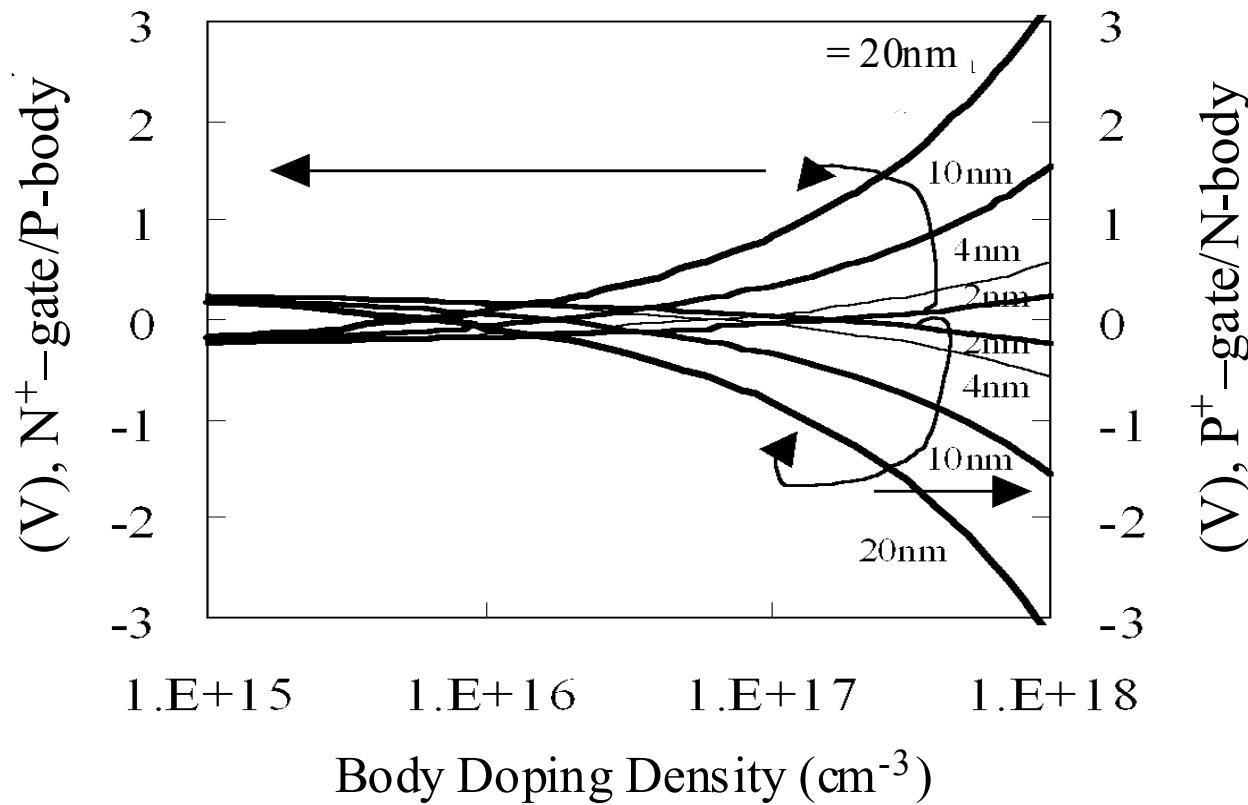
$$= \phi + 2\phi + \sqrt{\frac{2\varepsilon}{2\phi}}$$

Alternative definition of the threshold condition :

$$\phi = \phi + 0.45 \text{ V} = -\ln \frac{V}{2} + 0.45 \text{ V}$$

$$= \phi + 0.45 \text{ V} + \sqrt{\frac{2}{\phi}} \frac{2\varepsilon (\phi + 0.45 \text{ V})}{2\phi}$$

# *Threshold Voltage*

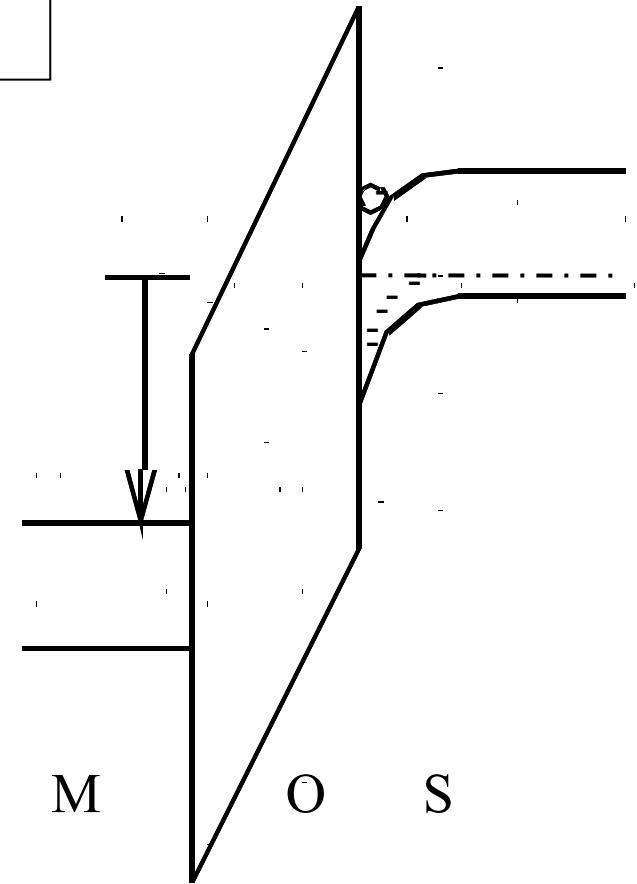
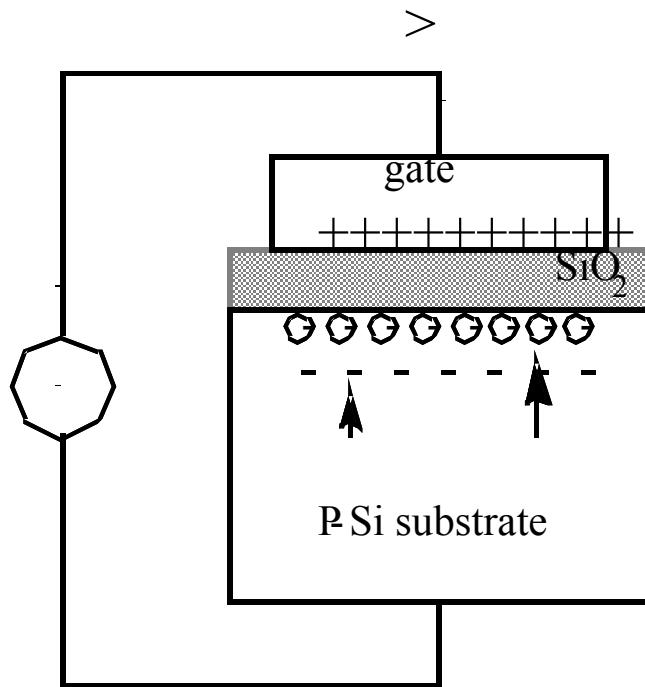


+ for P-body,  
- for N-body:

$$= \pm 2\phi \pm \frac{\sqrt{2\varepsilon 2\phi}}{ }$$

## 5.5 Strong Inversion—Beyond Threshold

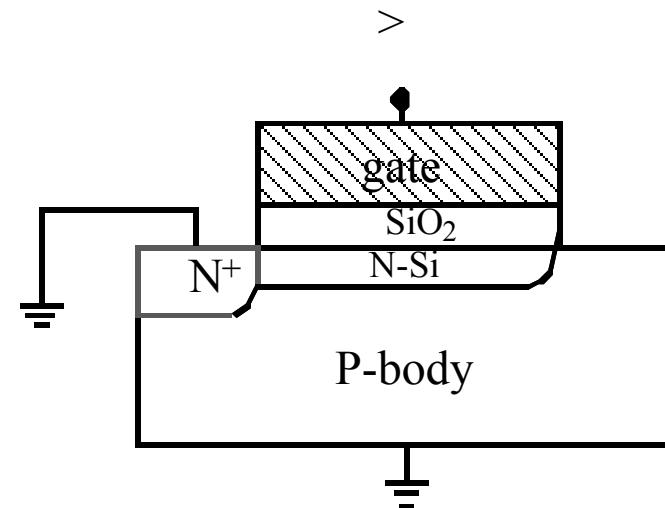
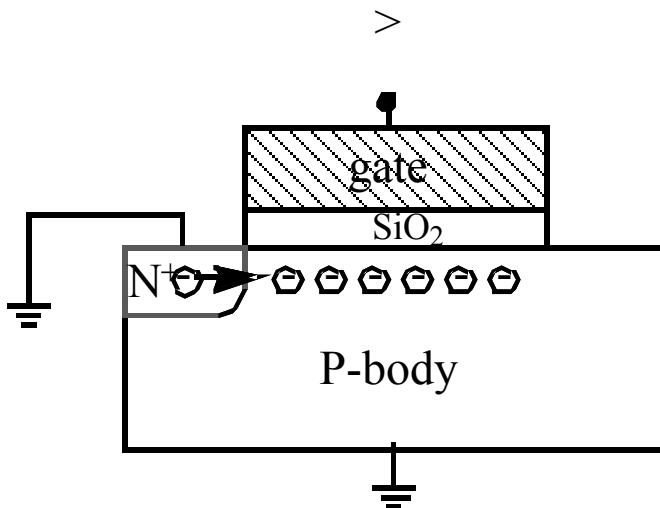
$$= \sqrt{\frac{2\epsilon \phi}{}}$$



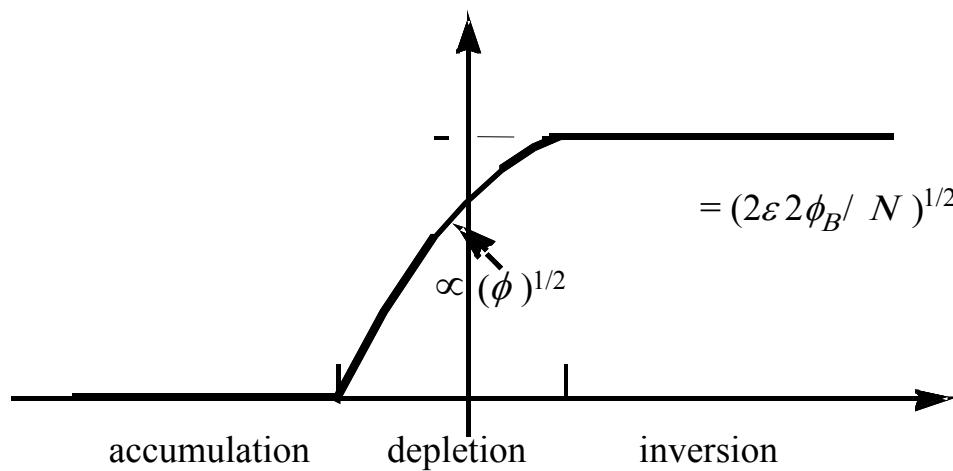
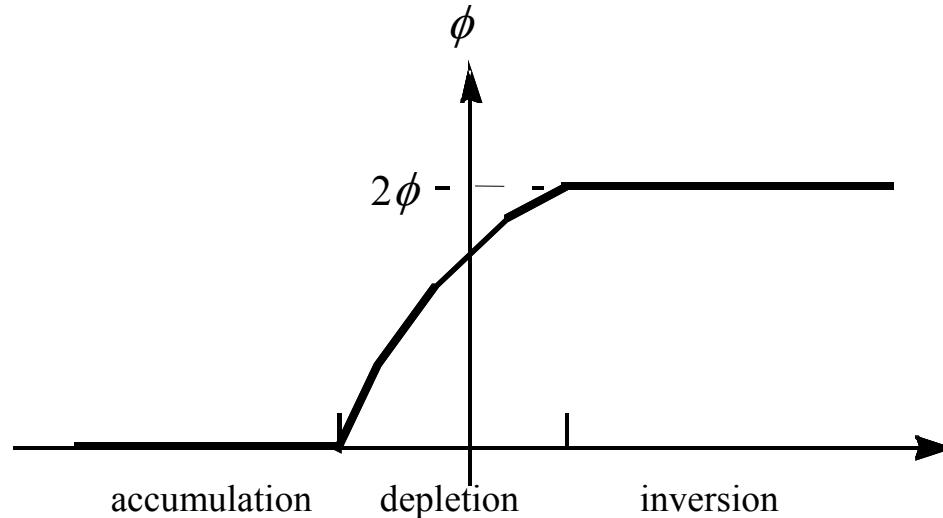
# *Inversion Layer Charge, $Q_{inv}$ ( $C/cm^2$ )*

$$= +\phi - \text{_____} = +\phi + \frac{\sqrt{2\epsilon\phi}}{\text{_____}}$$

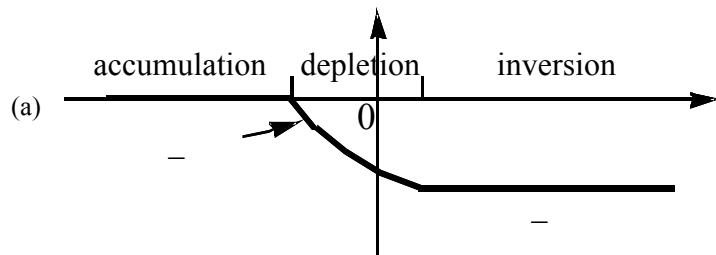
$$= \text{_____} \quad \therefore \quad \boxed{= - ( - )}$$



## *Review : Basic MOS Capacitor Theory*

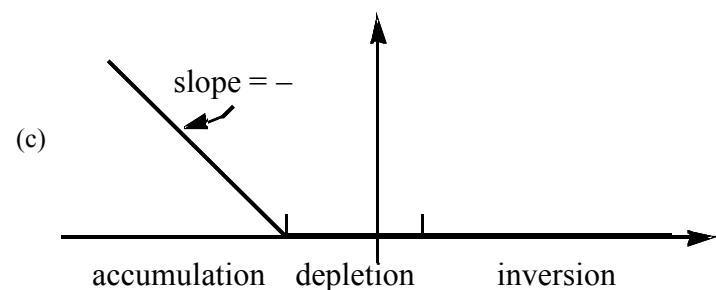
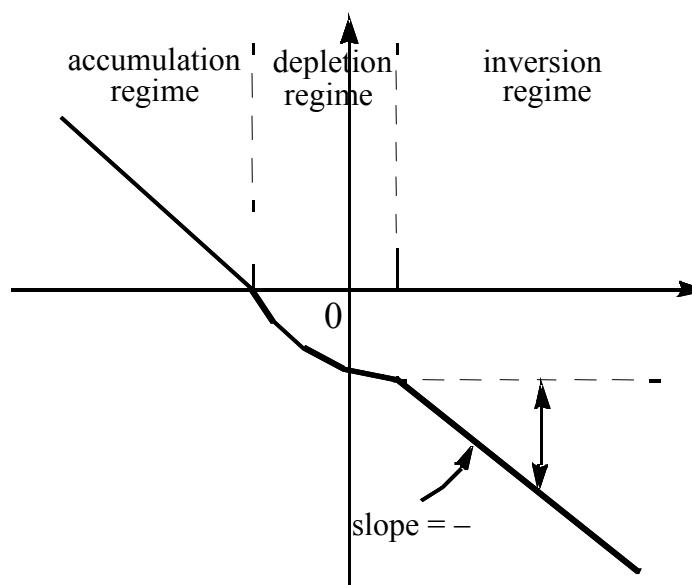
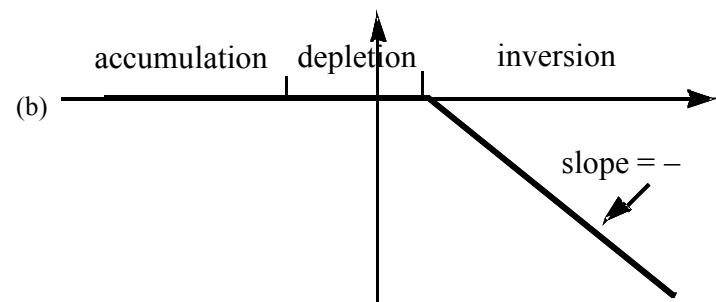


# *Review : Basic MOS Capacitor Theory*

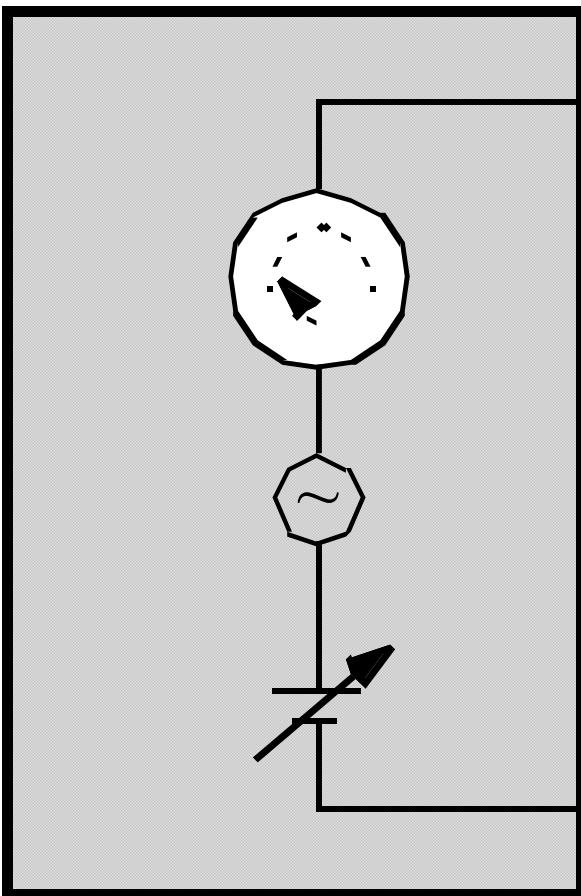


total substrate charge,

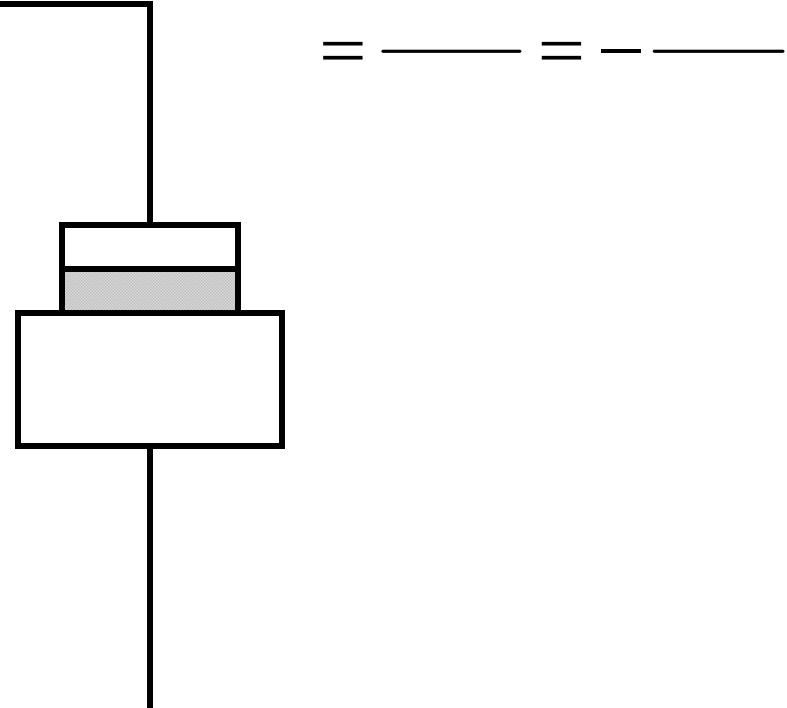
$$= + +$$



## 5.6 MOS CV Characteristics



CV Meter



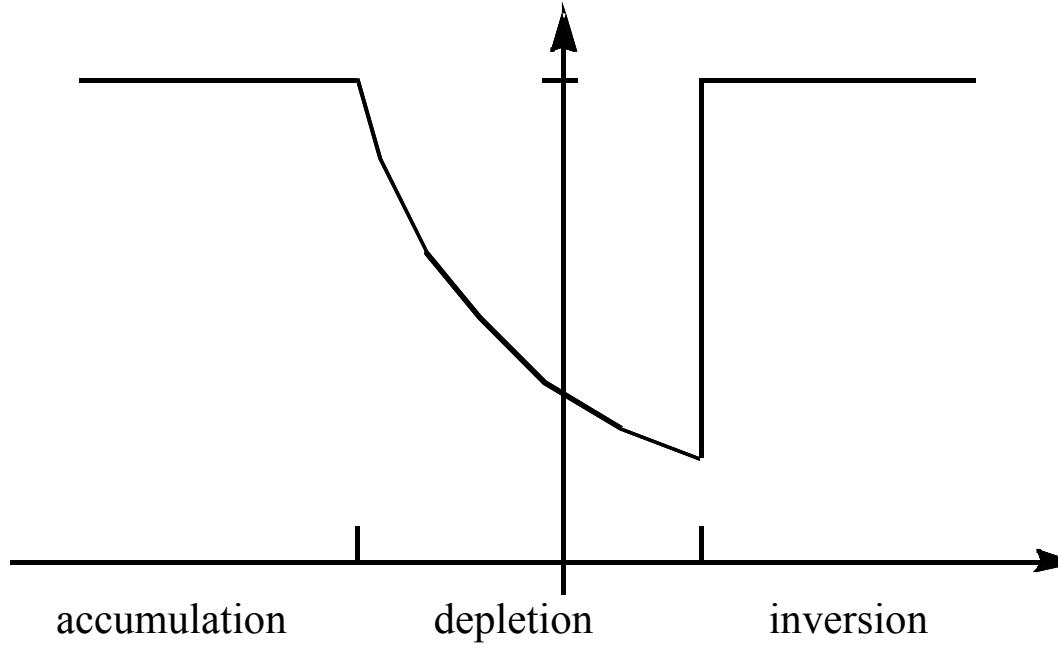
MOS Capacitor

## *5.6 MOS CV Characteristics*

= ————— = —————

A

## *CV Characteristics*

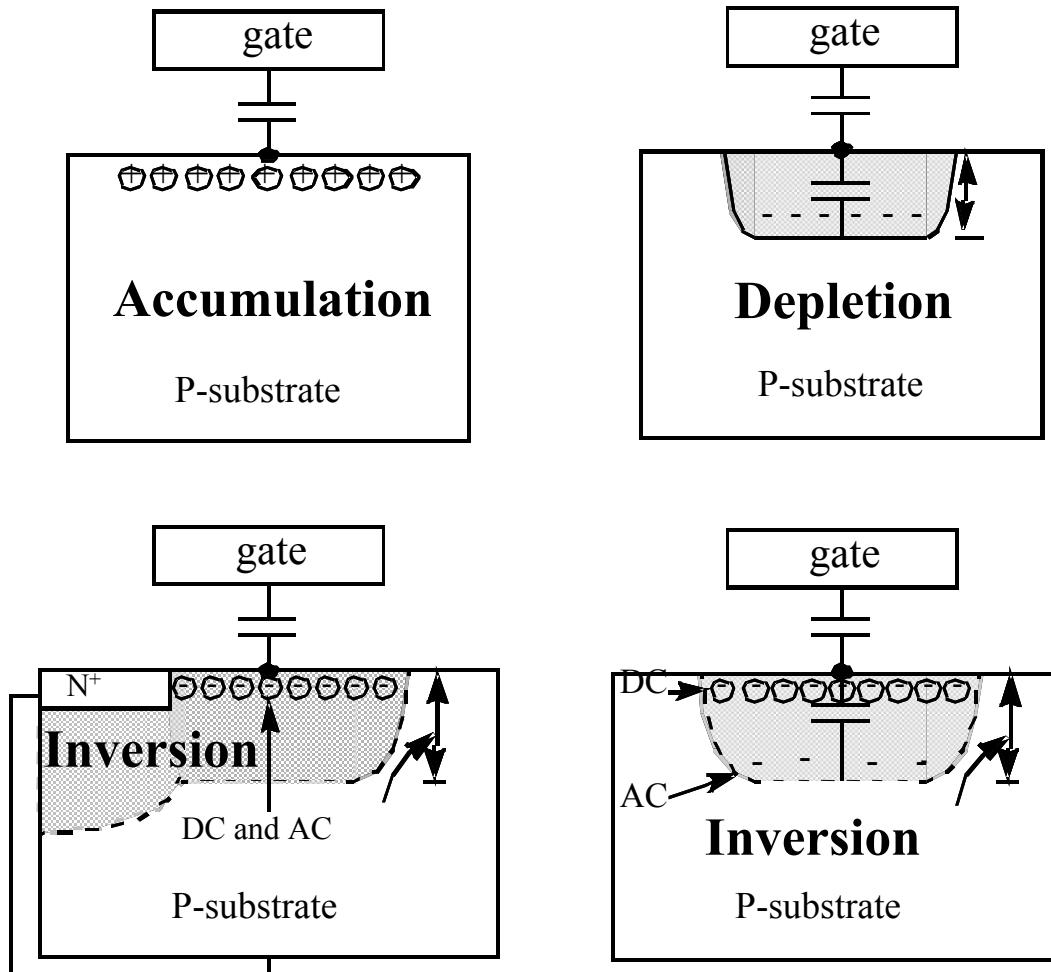


In the depletion regime:

$$\frac{1}{C} = \frac{1}{C_0} + \frac{1}{C_D}$$

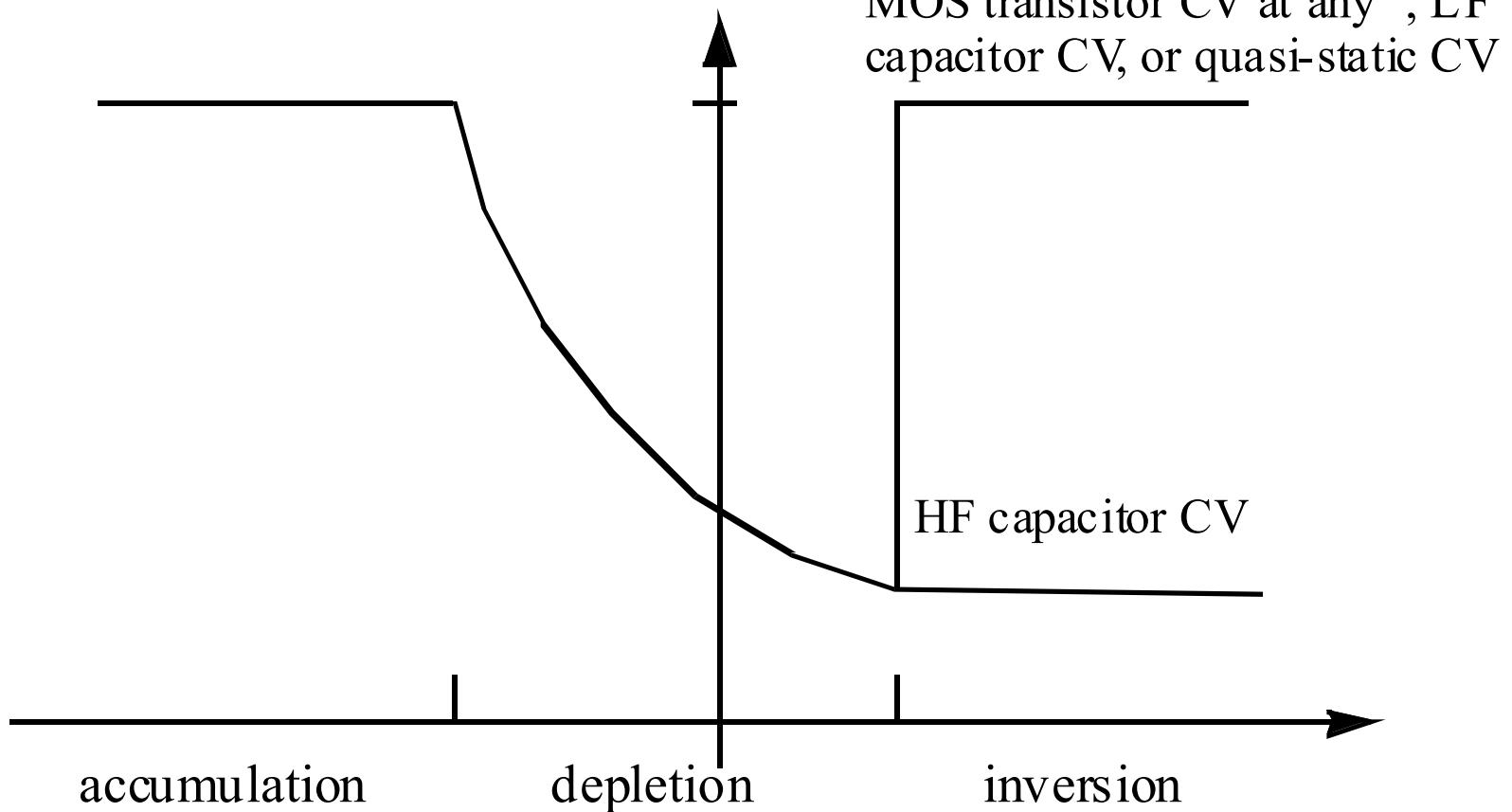
$$\frac{1}{C_D} = \sqrt{\frac{1}{2} + \frac{2(\phi - V)}{\epsilon}}$$

# *Supply of Inversion Charge May be Limited*

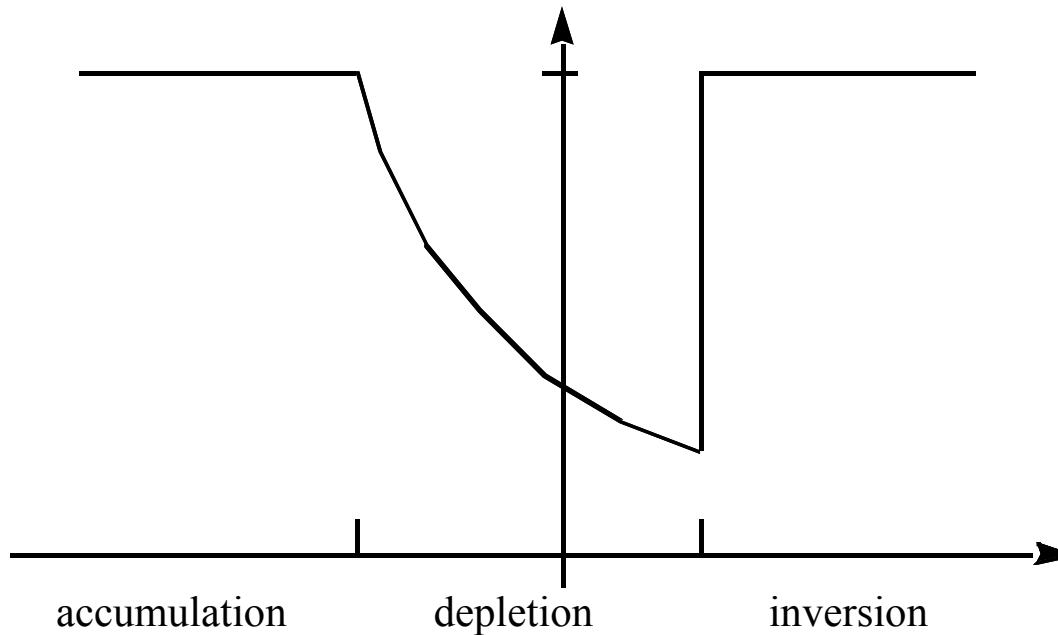


In each case, = ?

# *Capacitor and Transistor CV (or HF and LF CV)*

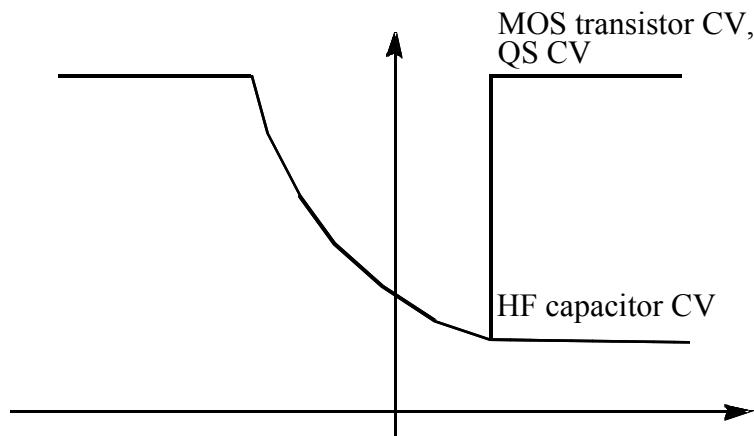


# *Quasi-Static CV of MOS Capacitor*

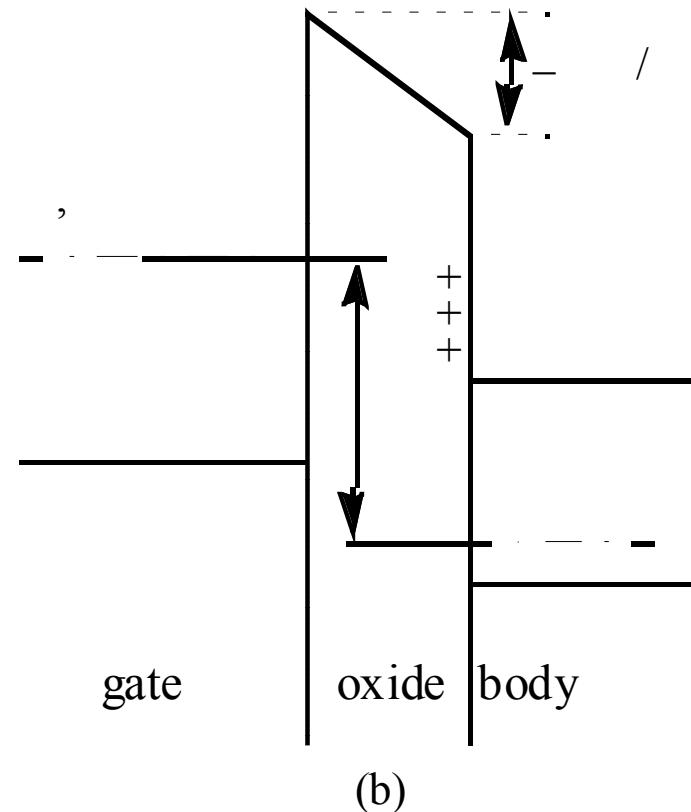
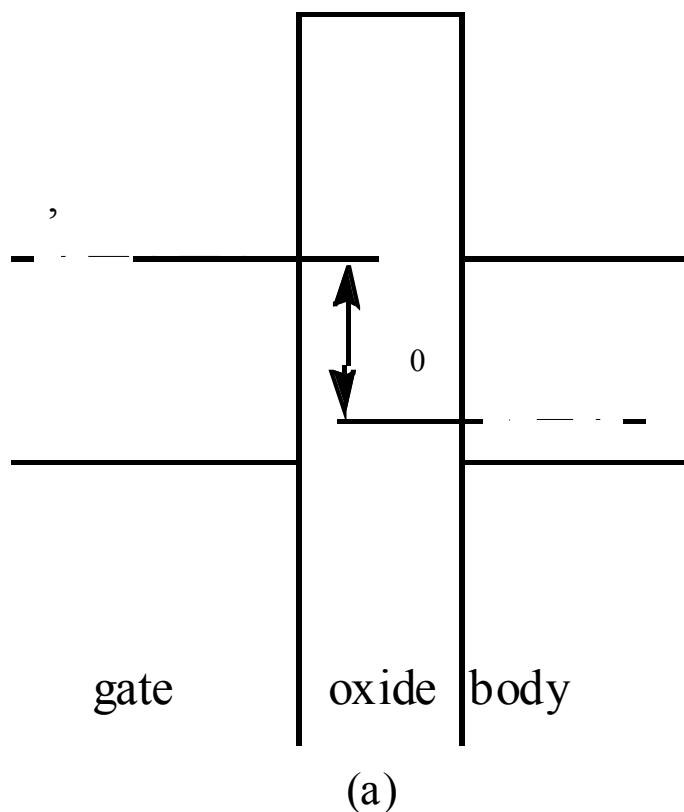


The quasi-static CV is obtained by the application of a slow linear-ramp voltage ( $< 0.1\text{V/s}$ ) to the gate, while measuring  $C$  with a very sensitive DC ammeter.  $C$  is calculated from  $C = \frac{Q}{V} = \frac{A\epsilon_0\epsilon_r}{d}$ . This allows sufficient time for  $C$  to respond to the slow-changing  $V$ .

## *EXAMPLE : CV of MOS Capacitor and Transistor*



## 5.7 Oxide Charge—A Modification to $V_{fb}$ and $V_t$



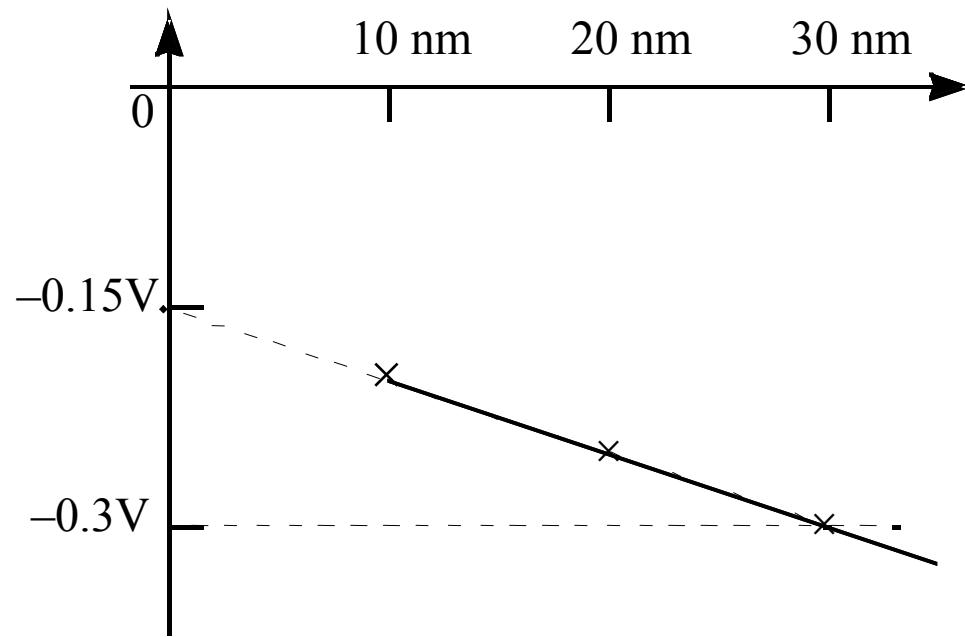
$$= \psi_0 - \psi_s / = \psi_s - \psi_t - \psi_b /$$

## *5.7 Oxide Charge—A Modification to $V_{fb}$ and $V_t$*

*Three types of oxide charge:*

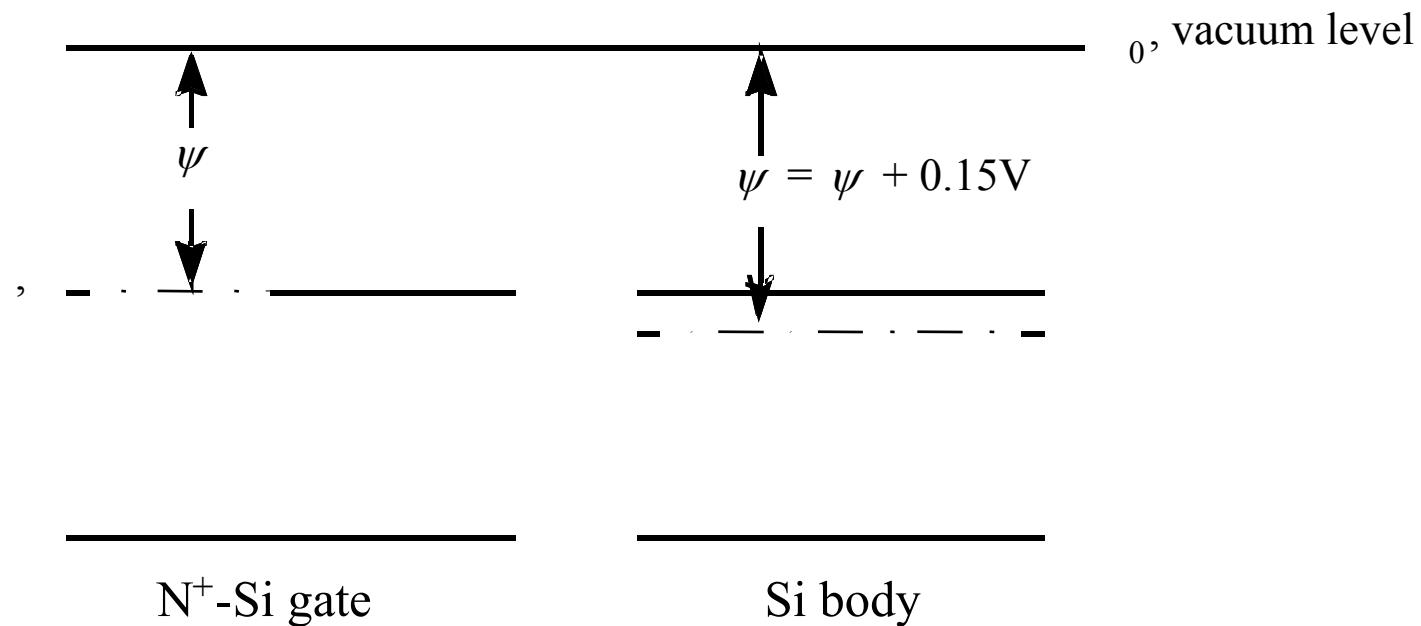
- Fixed oxide charge,  $\text{Si}^+$
- Mobile oxide charge,  $\text{Na}^+$   
(due to sodium contamination)
- Stress-induced charge—a reliability issue

## *EXAMPLE:*



*Solution:*  $= \psi_0 - \psi_{30} - \frac{q}{\epsilon}$

$$\rightarrow \psi - \psi = -0.15 \text{ V}$$



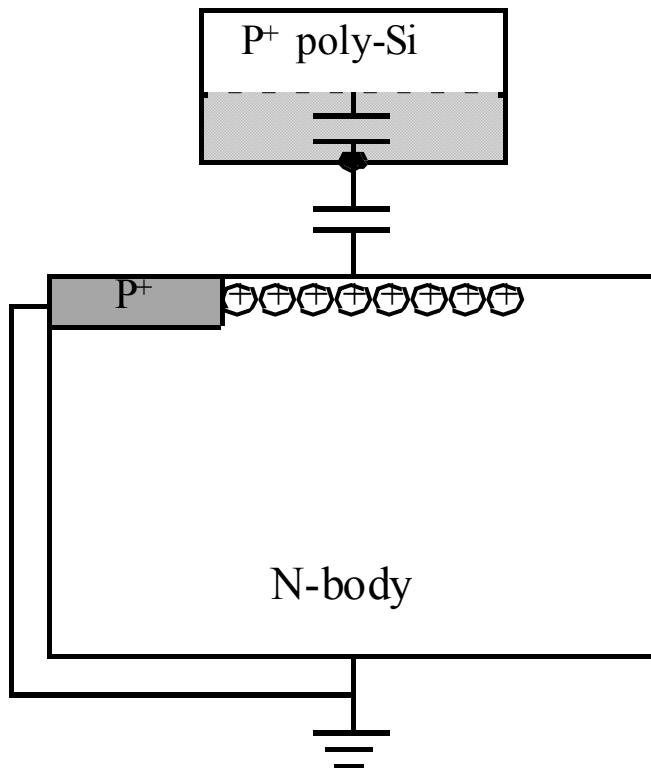
$$, \quad = \quad = \quad -0.15 \text{ eV} / \approx 10^{17} \text{ cm}^{-3}$$

$$\longrightarrow \quad = 1.7 \times 10^{-8} \text{ C/cm}^2$$

## 5.8 Poly-Silicon Gate Depletion-Effective Increase in $T_{ox}$

Gauss's Law

$$= \epsilon \cdot \epsilon /$$



$$= \left( \frac{1}{\epsilon} + \frac{1}{\epsilon} \right)^{-1} = \left( \frac{\epsilon}{\epsilon} + \frac{\epsilon}{\epsilon} \right)^{-1}$$

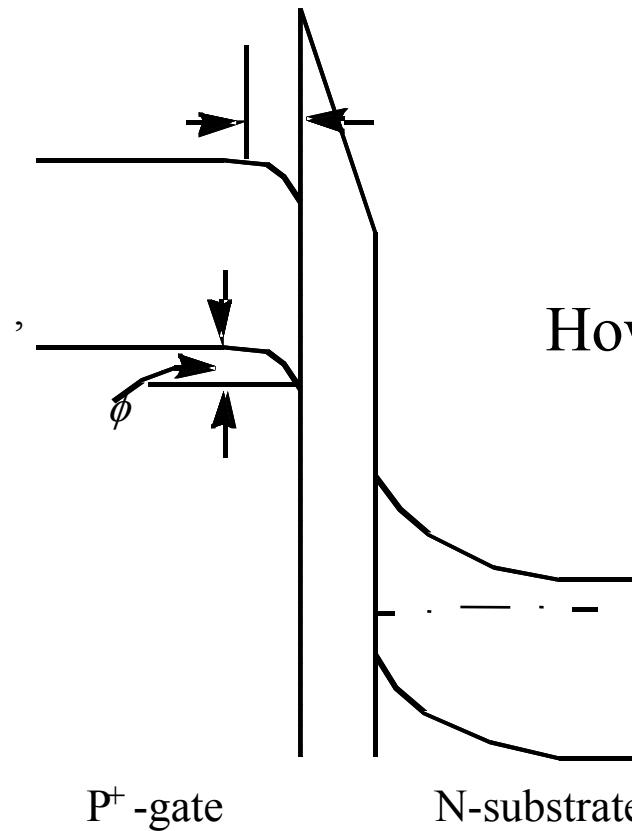
$$= \frac{\epsilon}{\epsilon + \epsilon / 3}$$

If  $\epsilon = 15 \text{ \AA}$ , what is the effective increase in  $\epsilon$ ?

Why is a reduction in  $\epsilon$  undesirable?

## *Effect of Poly-Gate Depletion on $Q_{inv}$*

$$= (-\phi - )$$



How can poly-depletion be minimized?

## *EXAMPLE : Poly-Silicon Gate Depletion*

$$= \times \\ \phi$$

+

*Solution:*

$$\begin{aligned} &= \epsilon \quad / \quad = \epsilon \quad / \\ &= \frac{3.9 \times 8.85 \times 10^{-14} (\text{F/cm}) \cdot 1 \text{ V}}{2 \times 10^{-7} \text{ cm} \cdot 1.6 \times 10^{-19} \text{ C} \cdot 8 \times 10^{19} \text{ cm}^{-3}} \\ &= 1.3 \text{ nm} \end{aligned}$$

## *EXAMPLE : Poly-Silicon Gate Depletion*

$$= \sqrt{\frac{2\epsilon \phi}{}}$$

$$\phi = V^2 / 2\epsilon = 0.11 \text{ V}$$

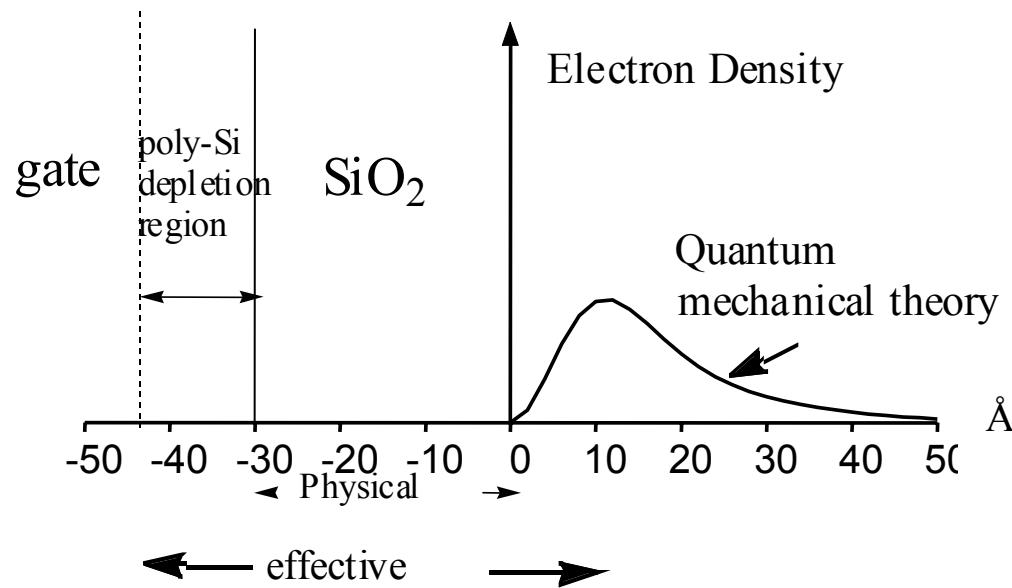
$$= +\phi + \phi$$

$$= -\ln\left(\frac{-}{-}\right) = 1.1 \text{ V} - 0.15 \text{ V} = 0.95 \text{ V}$$

$$= 0.95 \text{ V} - 0.85 \text{ V} - 1 \text{ V} - 0.11 \text{ V} = -1.01 \text{ V}$$

## 5.9 Inversion and Accumulation Charge-Layer Thickness–Quantum Mechanical Effect

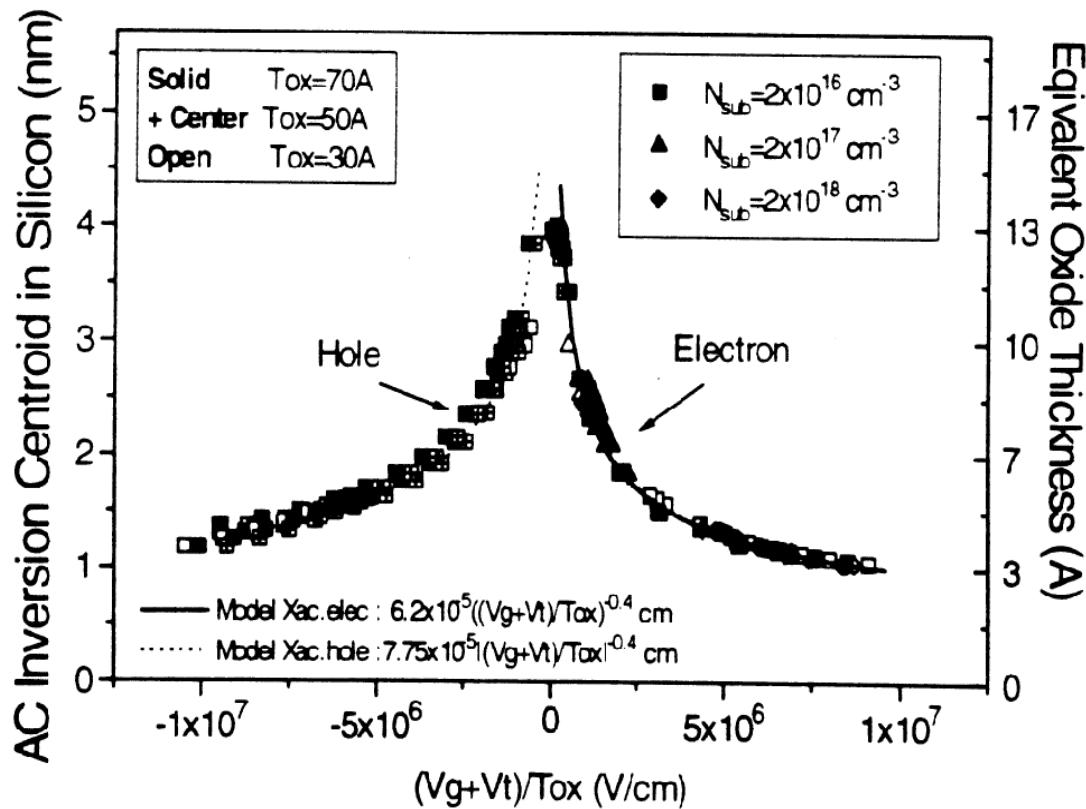
Average inversion-layer location below the Si/SiO<sub>2</sub> interface is called the *inversion-layer thickness*,  $T$  .



What equations need to be solved to find  $( )$ ?  
Does  $\quad$  change with varying  $\quad$  ?

## Electrical Oxide Thickness, $T_{oxe}$

$$= + / 3 + / 3 \text{ at}$$

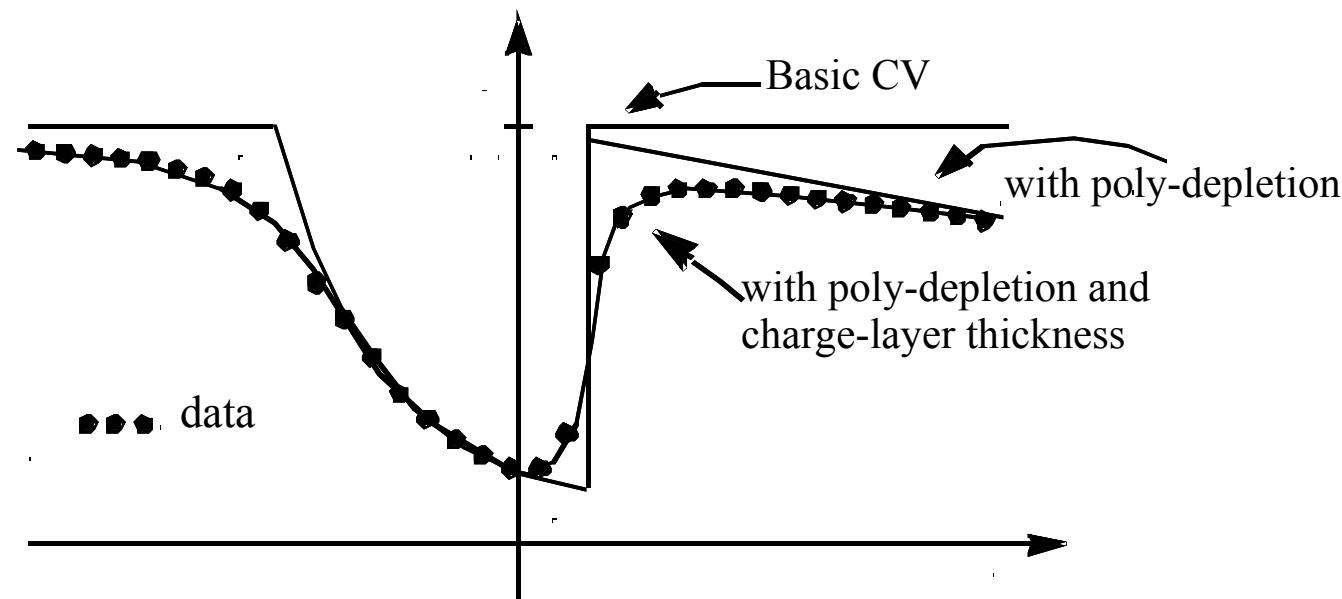


( + )/ can be shown to be the average electric field in the inversion layer. of holes is larger than that of electrons because of difference in effective mass.

## *Effective Oxide Thickness and Effective Oxide Capacitance*

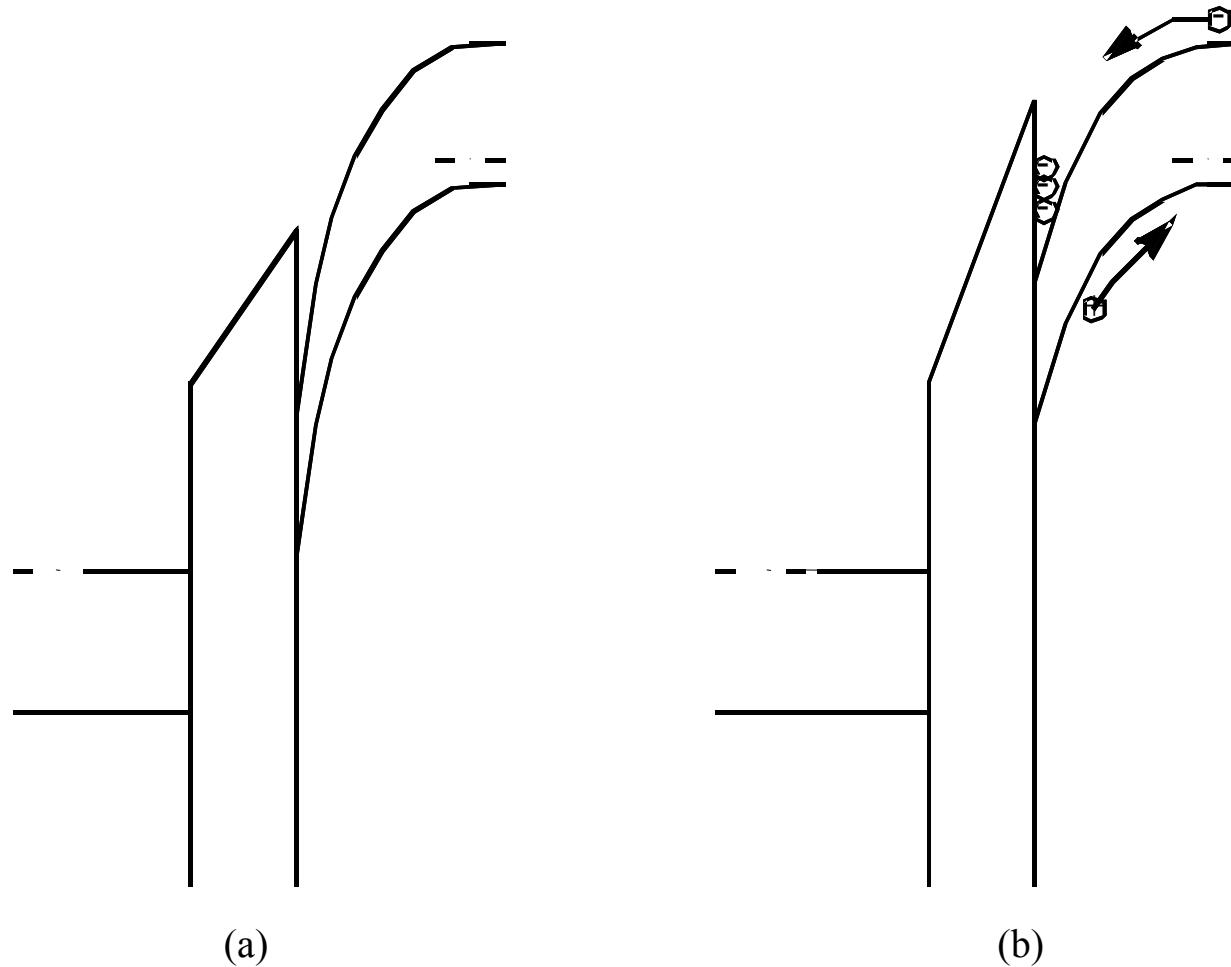
$$= \left( - \right)$$

$$= + / 3 + / 3$$



Which is worse in reduction : P<sup>+</sup>-poly over N-body or N<sup>+</sup>-poly over P-body?

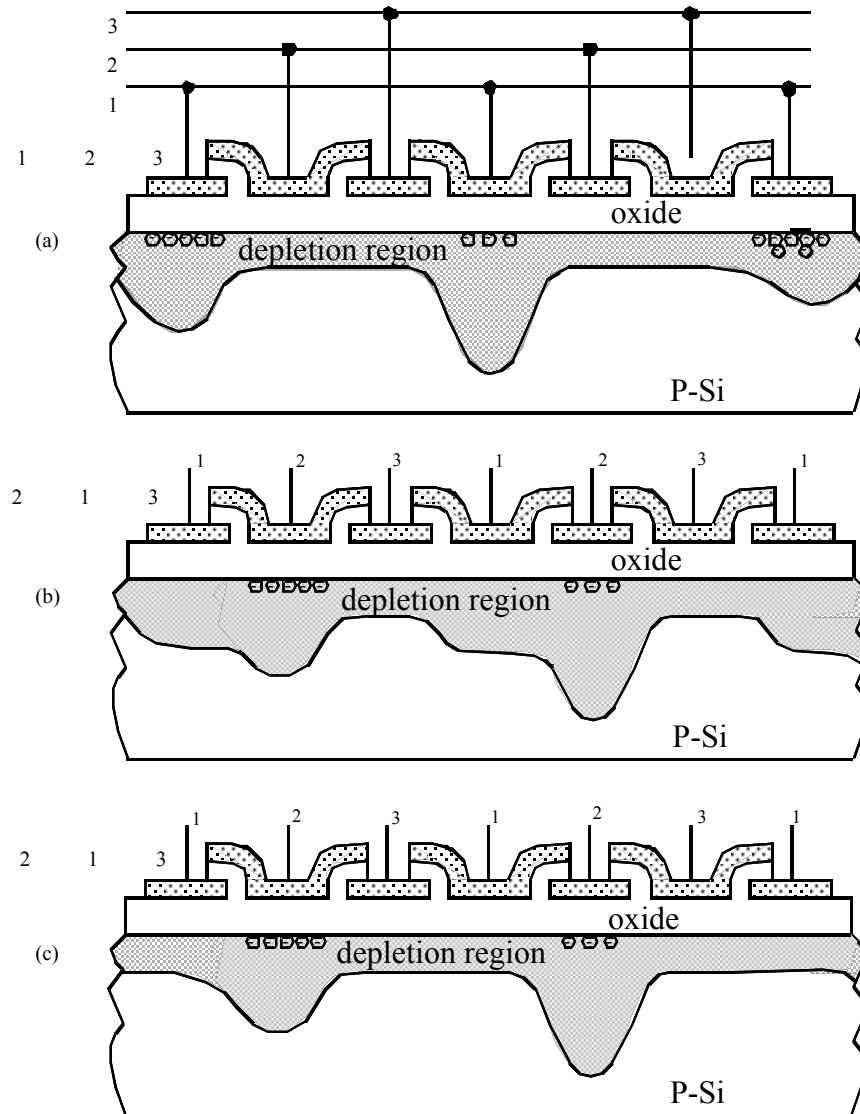
## 5.10 CCD Imager



Deep depletion,  $V = 0$

Exposed to light

# *CCD Charge Transfer*



## 5.11 Chapter Summary

N-type device: N<sup>+</sup>-polysilicon gate over P-body

P-type device: P<sup>+</sup>-polysilicon gate over N-body

$$= \psi - \psi (- / )$$

$$= +\phi + (+\phi )$$

$$= +\phi - / (+\phi )$$

## 5.11 Chapter Summary

$$\phi = \pm 2\phi \quad \text{or} \quad \pm (\phi + 0.45 \text{ V})$$

$$\phi = -\ln \frac{\rho}{\rho_0}$$

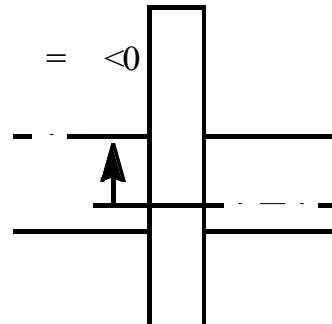
$$= \phi \pm \sqrt{\frac{2e|\phi|}{n}}$$

+ : N-type device, - : P-type device

## 5.11 Chapter Summary

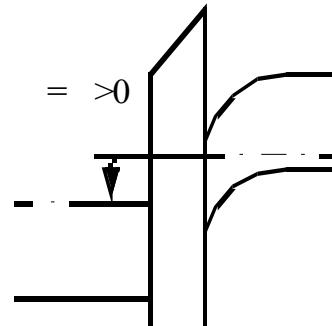
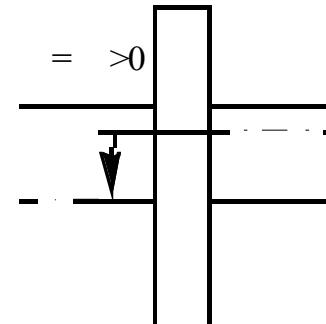
### N-type Device

(N<sup>+</sup>-gate over P-substrate)

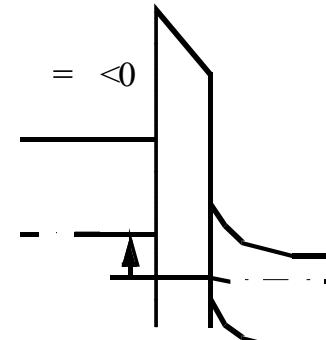


### P-type Device

(P<sup>+</sup>-gate over N-substrate)



Threshold

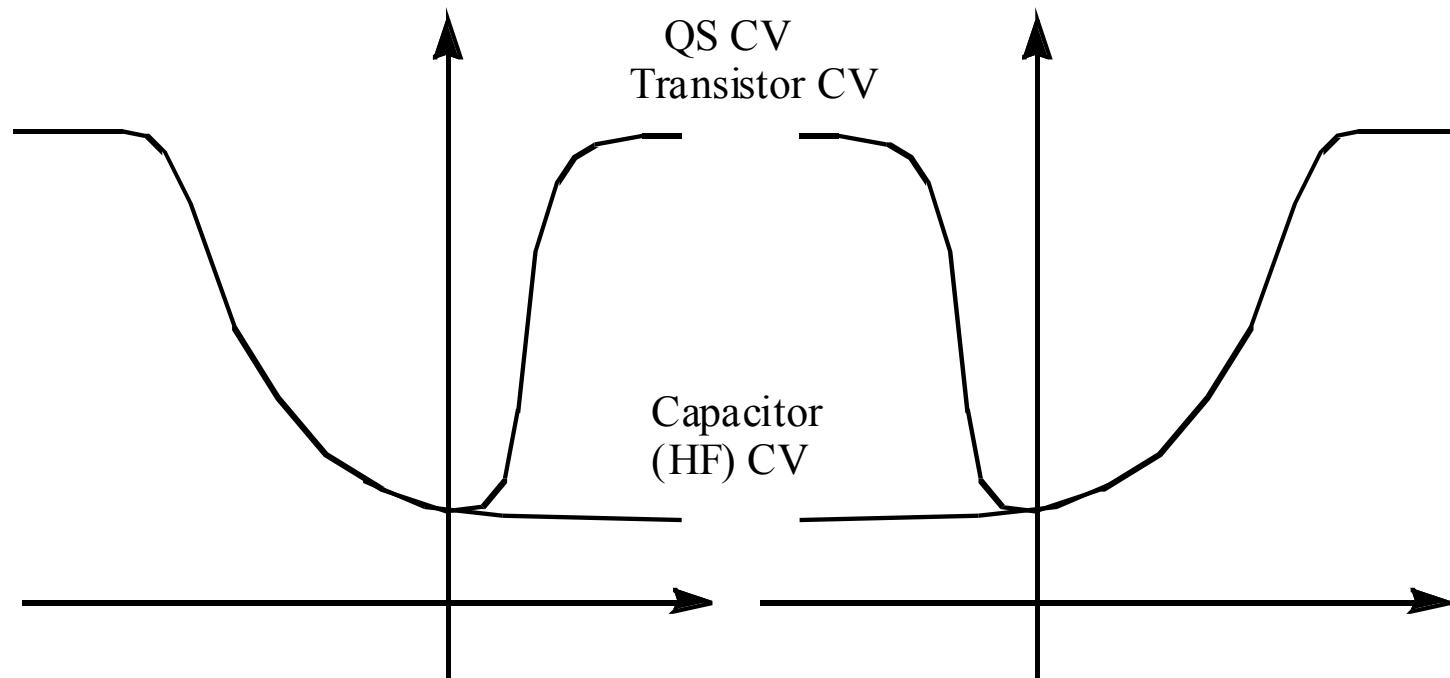


What's the diagram like at  $V_g > ?$  at  $V_g = 0?$

## 5.11 Chapter Summary

**N-type Device**  
(N<sup>+</sup>-gate over P-substrate)

**P-type Device**  
(P<sup>+</sup>-gate over N-substrate)



What is the root cause of the low  $C_V$  in the HF CV branch?